

Fig. 1

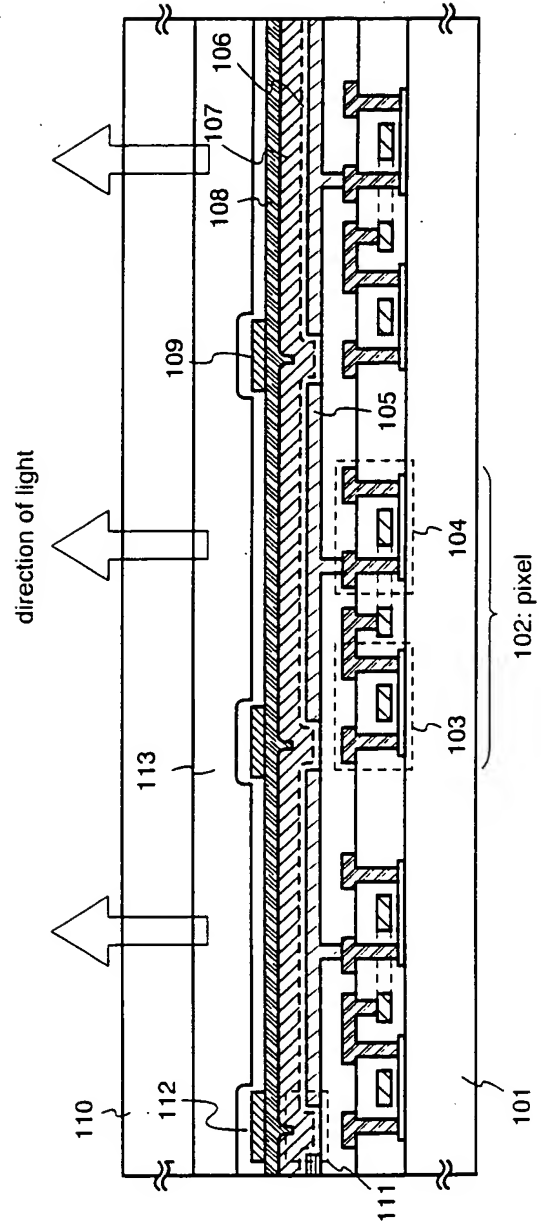
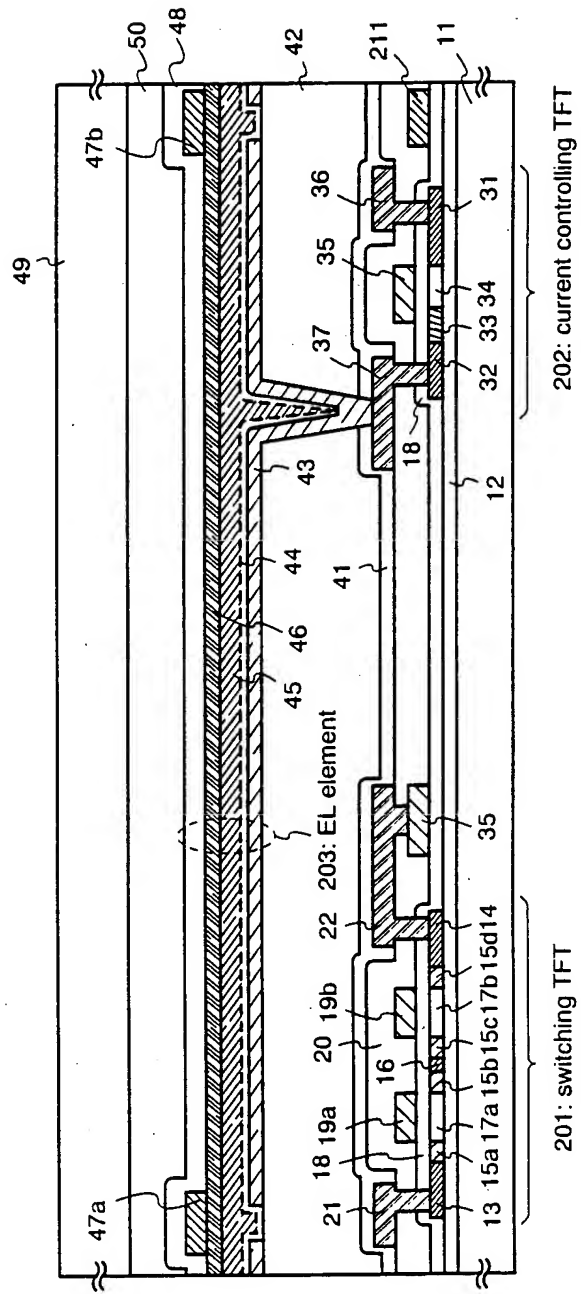


Fig. 2



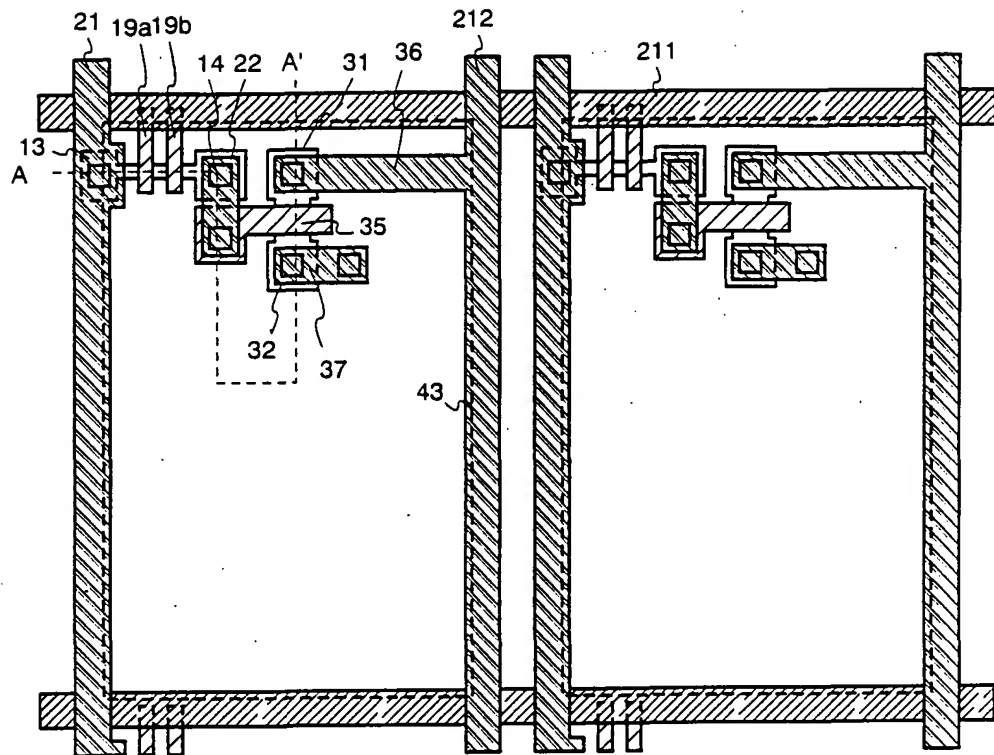


Fig. 3A

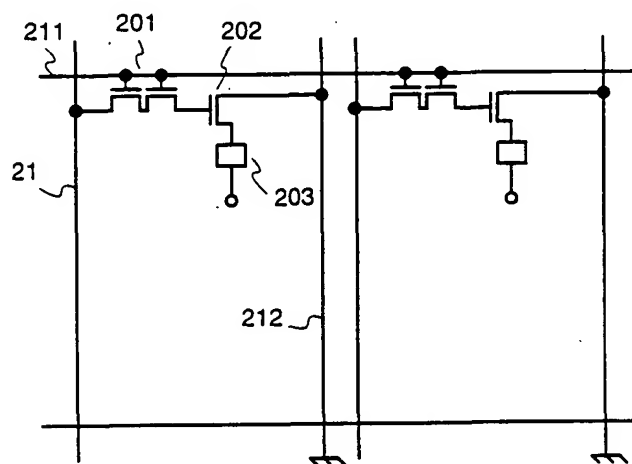


Fig. 3B

crystallization process

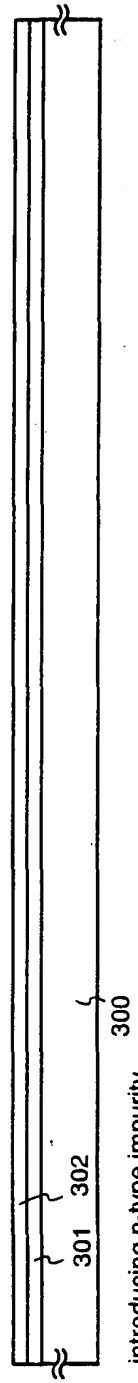


Fig. 4A

introducing n-type impurity

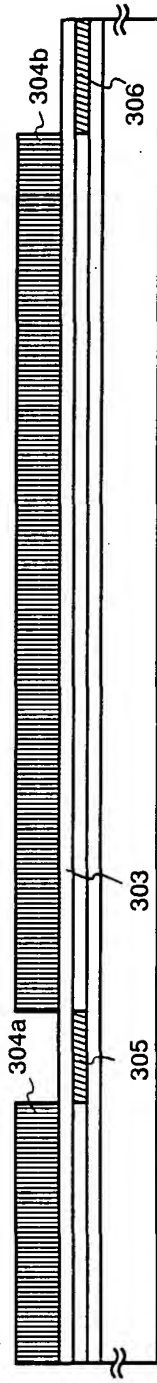


Fig. 4B

laser annealing process



Fig. 4C



Fig. 4D

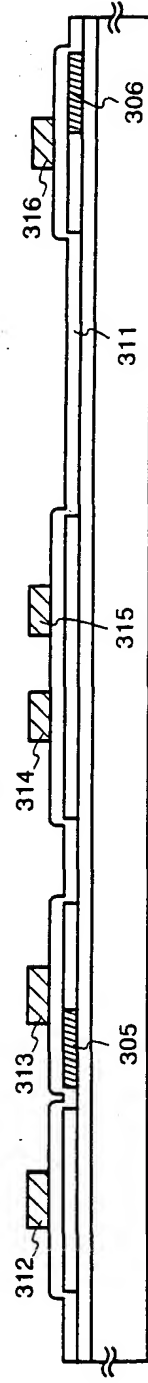


Fig. 4E

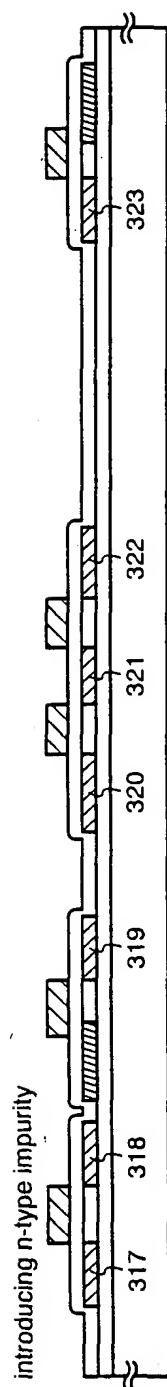


Fig. 5A

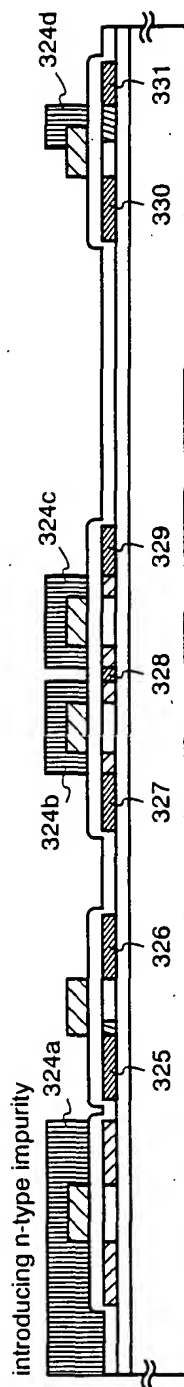


Fig. 5B

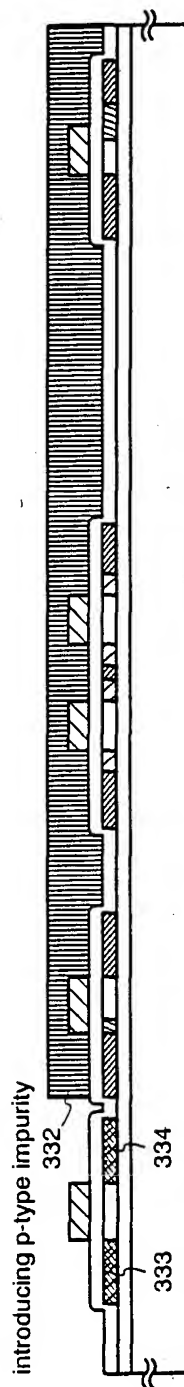


Fig. 5C

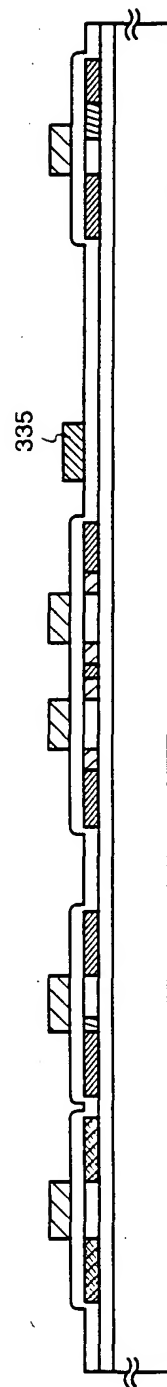


Fig. 5D

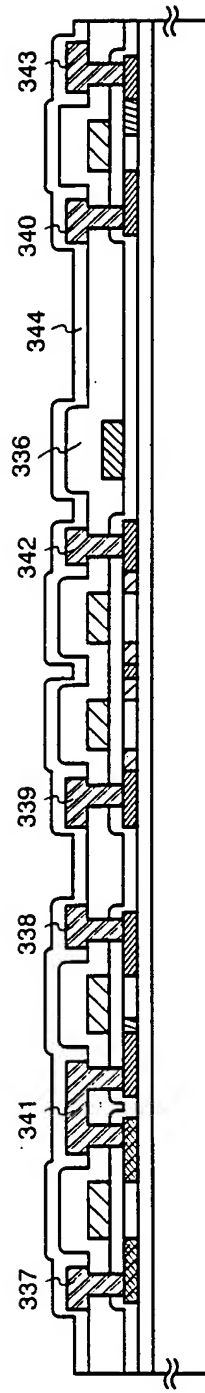


Fig. 6A

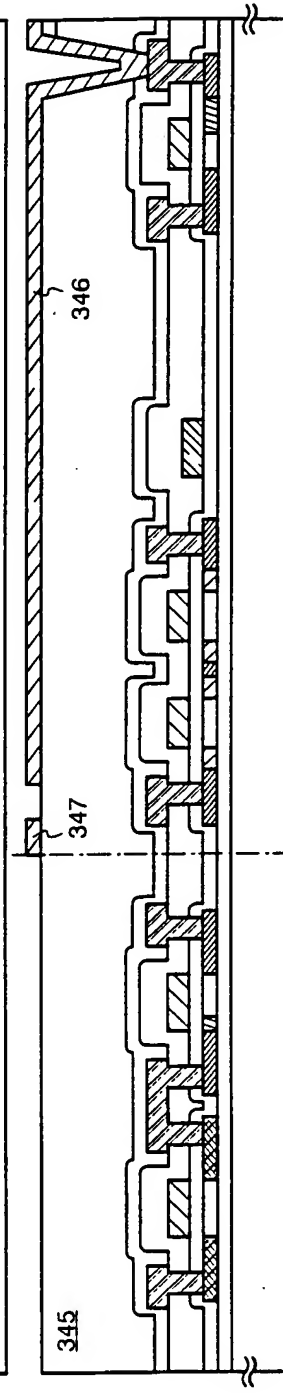


Fig. 6B

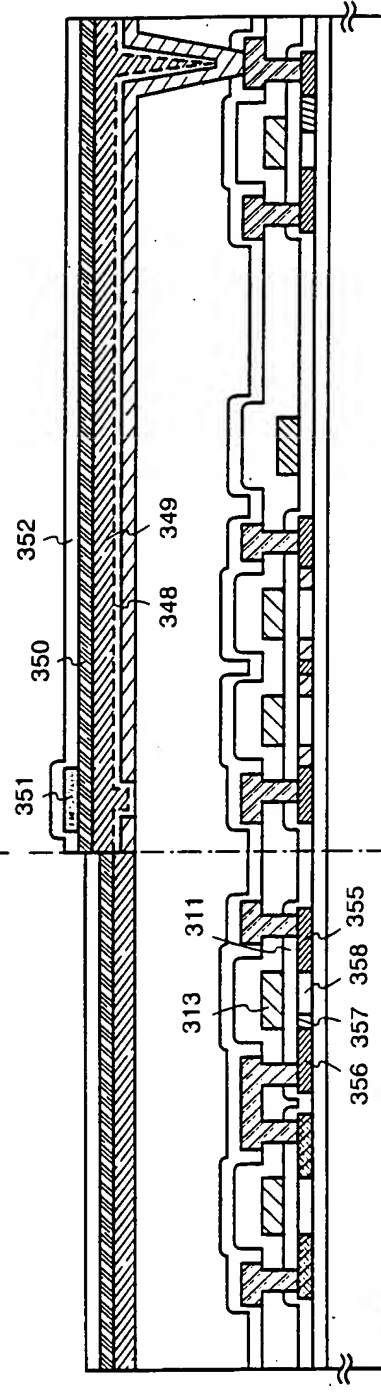


Fig. 6C

206: p-channel TFT 205: n-channel TFT

Fig. 7

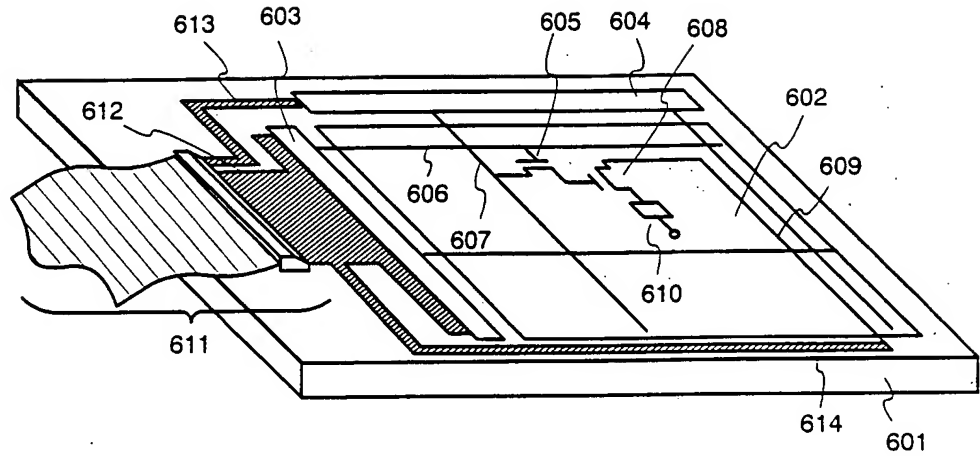


Fig. 8

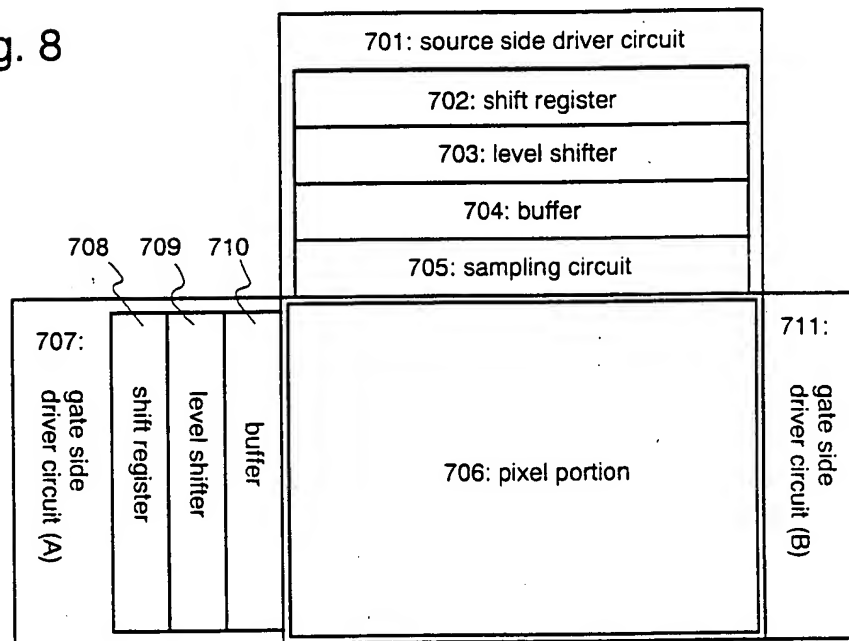


Fig. 9

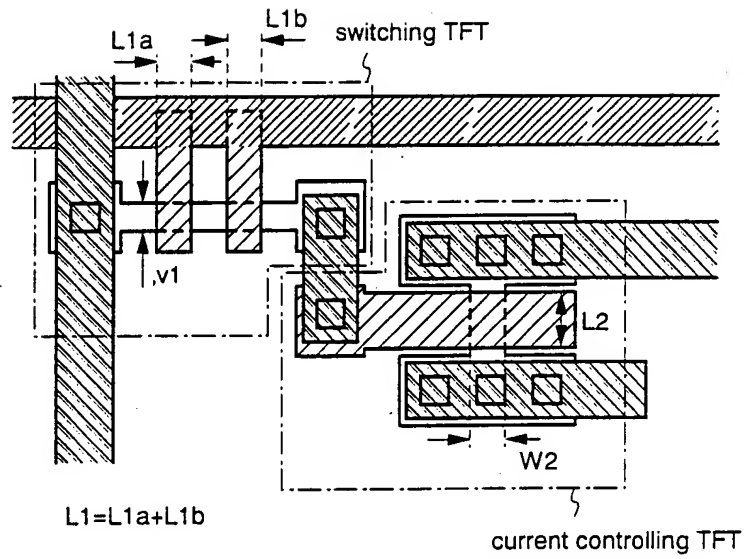
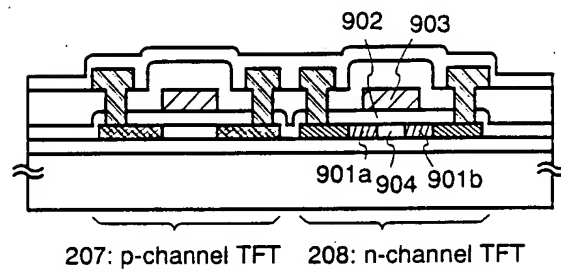


Fig. 10



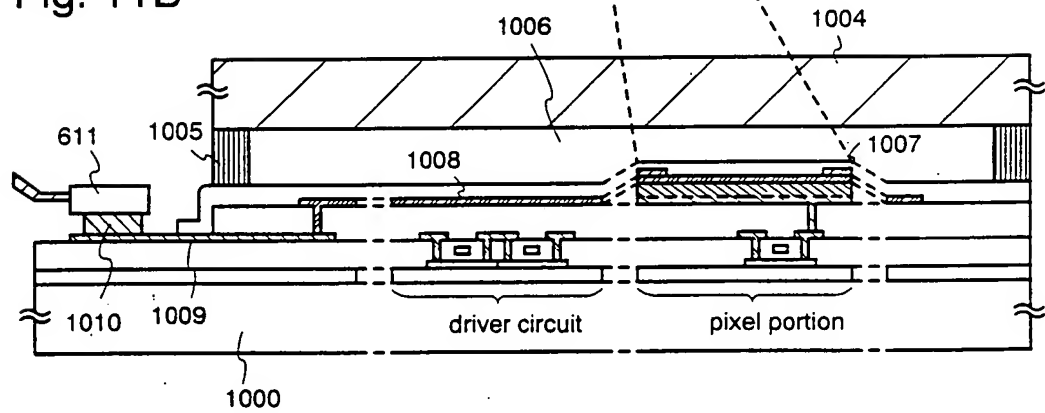
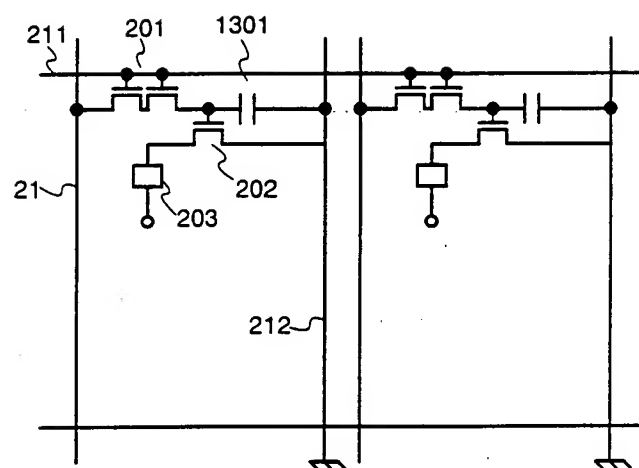


Fig. 12



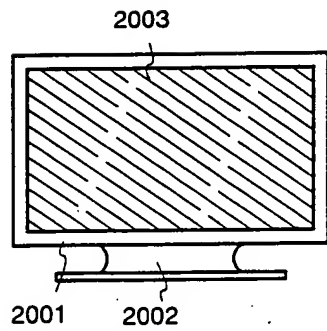


Fig. 13A

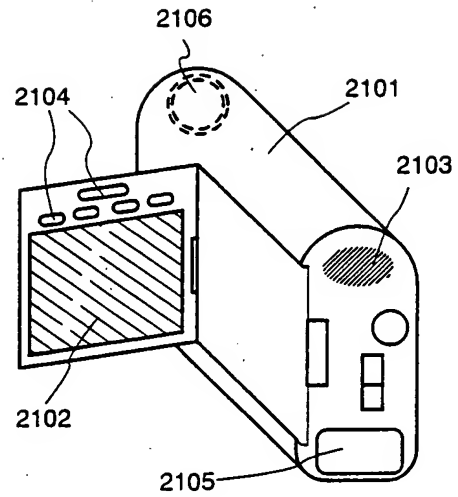


Fig. 13B

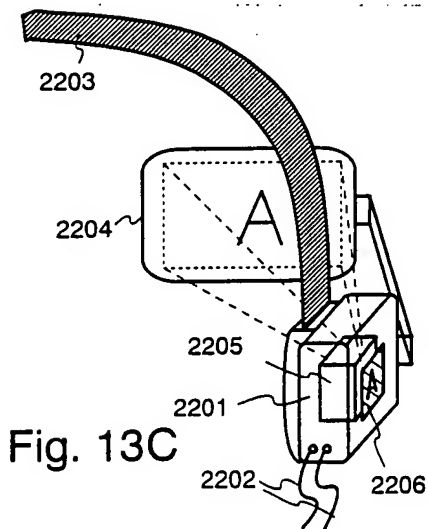


Fig. 13C

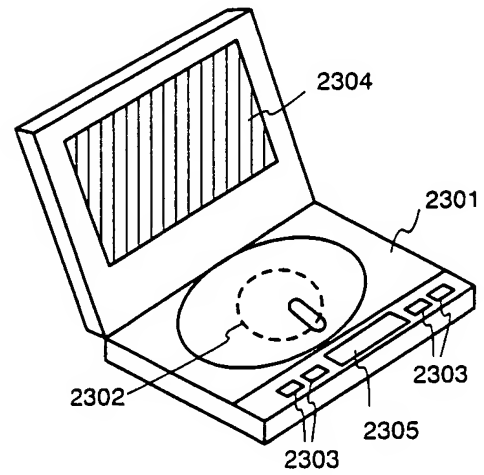


Fig. 13D

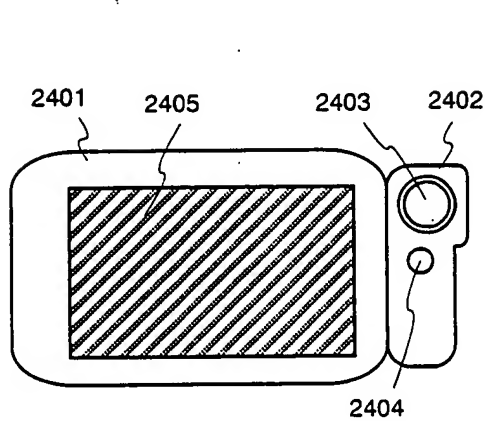


Fig. 13E

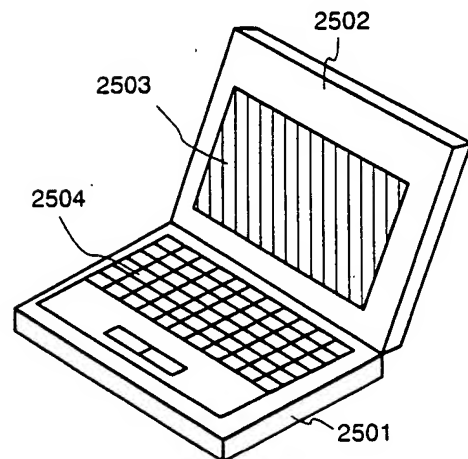


Fig. 13F

Fig. 14A

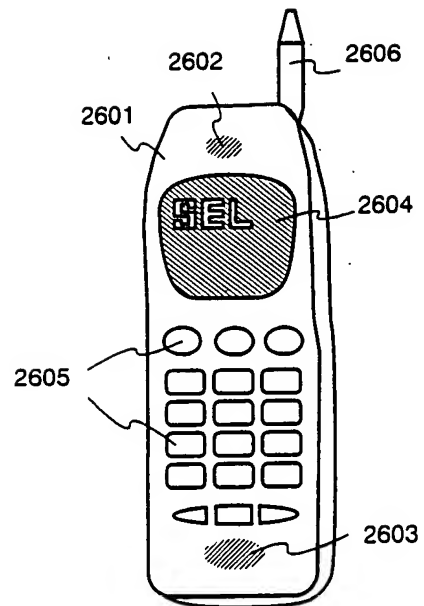


Fig. 14B

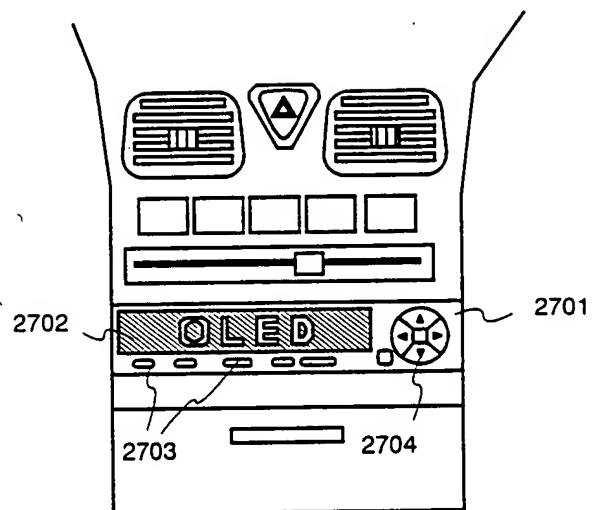


Fig. 15

